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Two articles in the Special Section on the Interface of Holography and MEMS were originally published online with erroneous citation identifiers (CIDs).

“Optical frequency comb profilometry with a compressive-sensing-based single-pixel camera composed of digital micromirror devices and a two-frequency method for meter-order depth measurements” by Quang Duc Pham and Yoshio

Hayasaki was published with a CID of 031301 and was republished with a CID of 041305 on 10 August 2015.

“Photorefractive holographic camera for monitoring deformations of MEMS” by Marc P. Georges and Cédric Thizy was published with a CID of 041301 and was republished with a CID of 041306 on 11 August 2015.

The article CIDs are correct in print.